

# Advanced characterization to underpin the mechanisms of *ultrafast Transient Liquid Assisted Growth (TLAG)* of superconducting epitaxial layers

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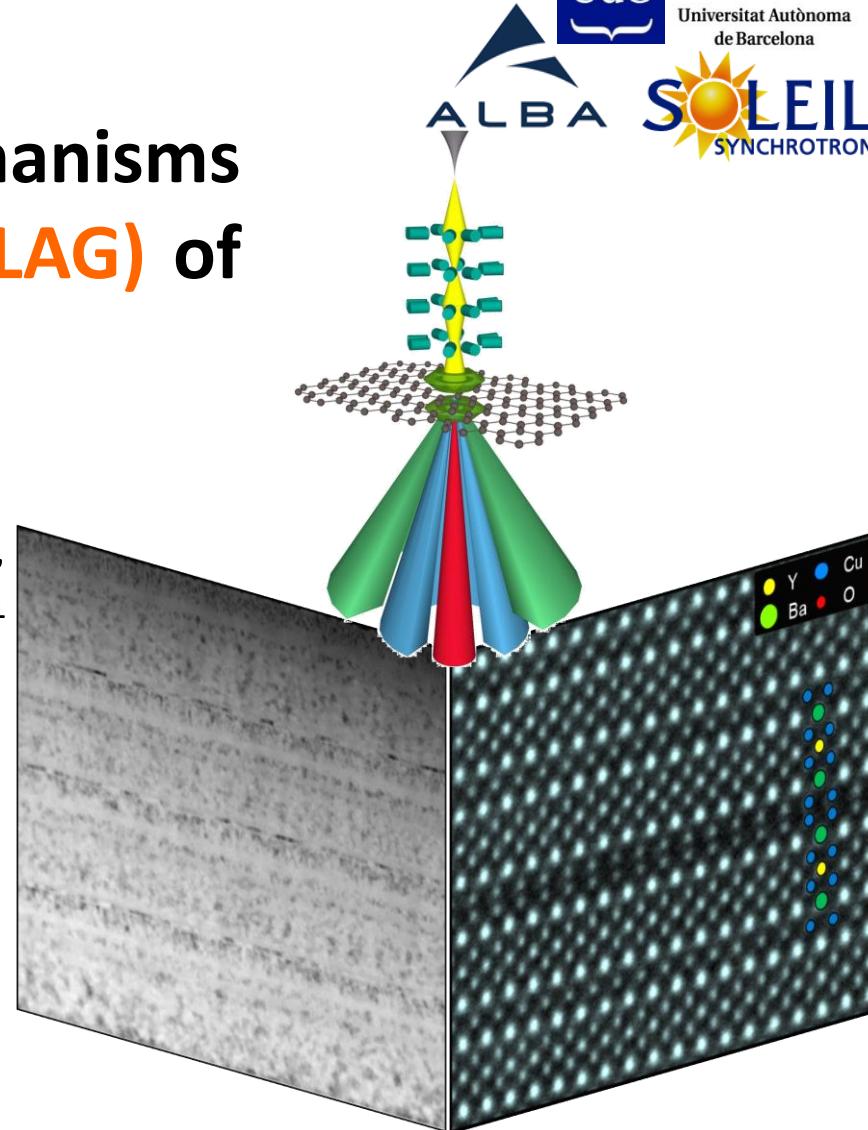
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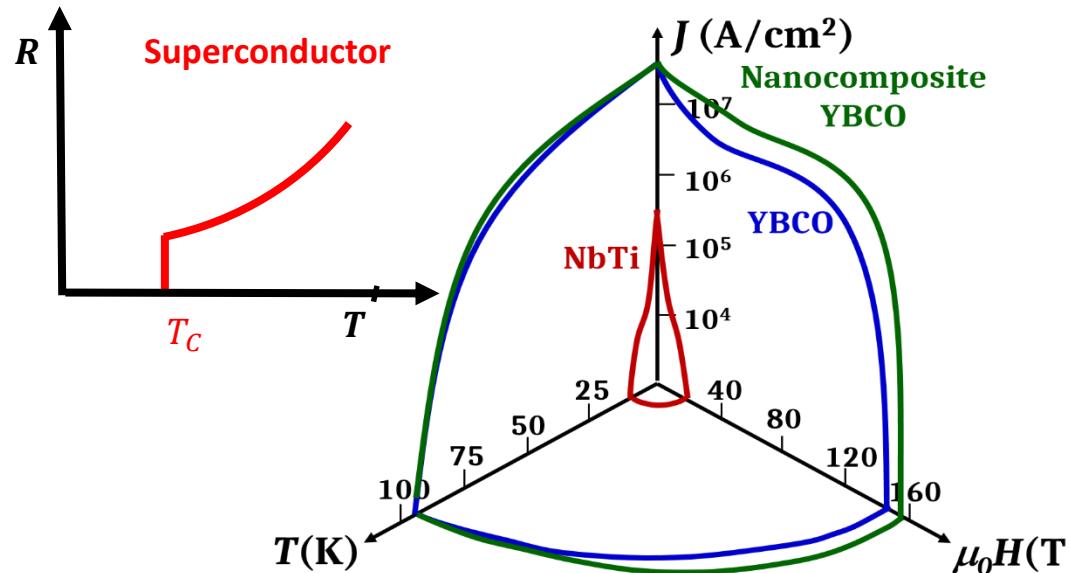
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# High Temperature Superconductors for Energy Transition



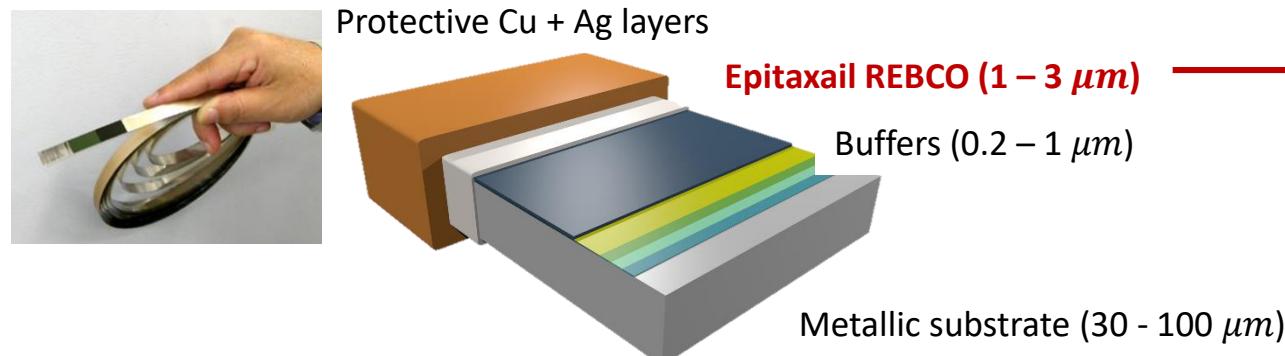
Devices with:  
-low losses  
-high magnetic fields  
-low weight, volume

**Distribution**  
Cables  
Fault Current Limiters

**Generation**  
Wind generators  
Compact Fusion

**Transportation**  
motors and generation  
in electrical aircraft

## Long length Coated Conductor (CC)

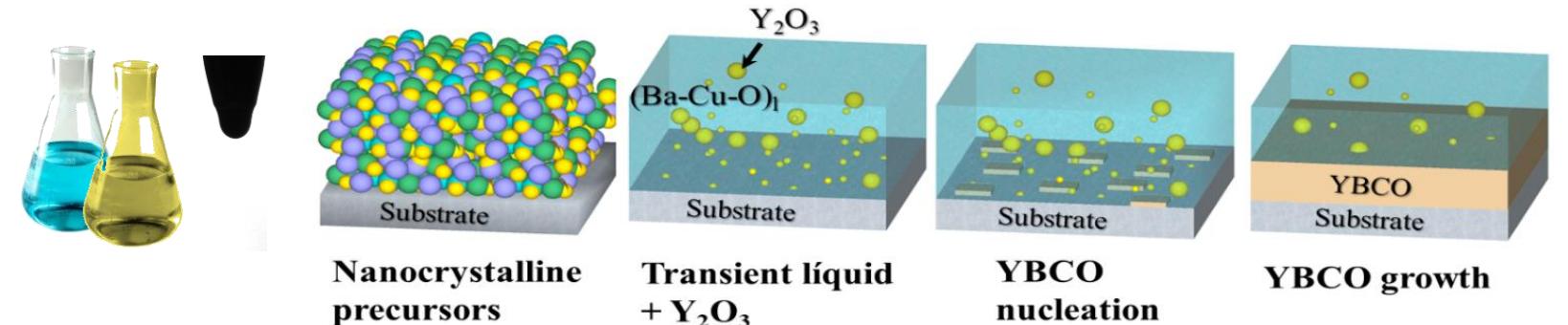


Low cost  
High throughput  
Scalability

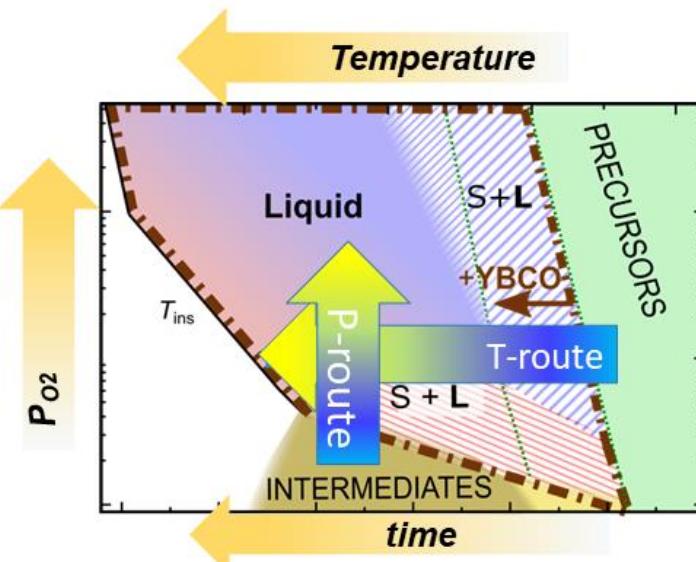
- PLD (5-15 nm/s)
- MOCVD (1-10 nm/s)
- Evaporation (5 nm/s)
- TFA- Chemical Solution Deposition (1 nm/s)

# TRANSIENT LIQUID ASSISTED GROWTH: TLAG

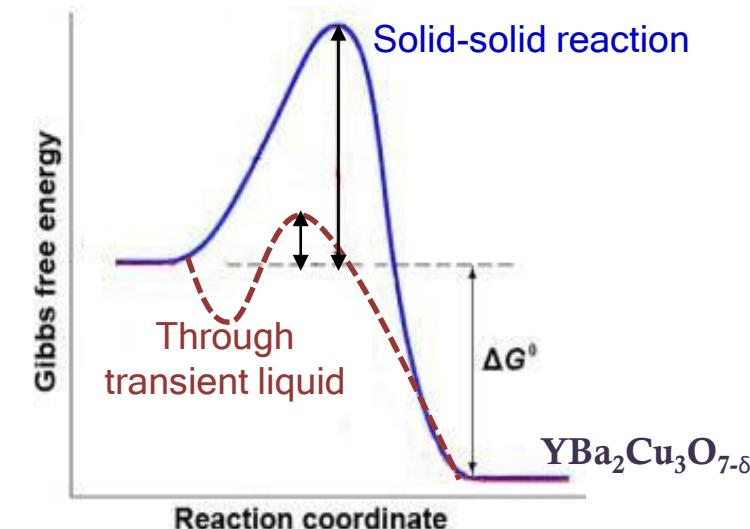
A non-equilibrium kinetically controlled process for ultrafast growth



(M-Prop) →

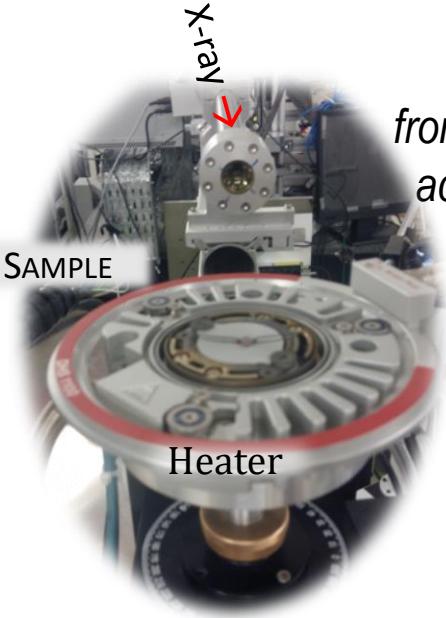


- Ultrafast growth rate,  $G$ , up to 2000 nm/s demonstrated
  - Large area deposition, simple reactor
  - High throughput
  - Low cost
- But,
- Kinetic growth mechanism need to be elucidated
  - Nano-microstructure is crucial because it determines performance



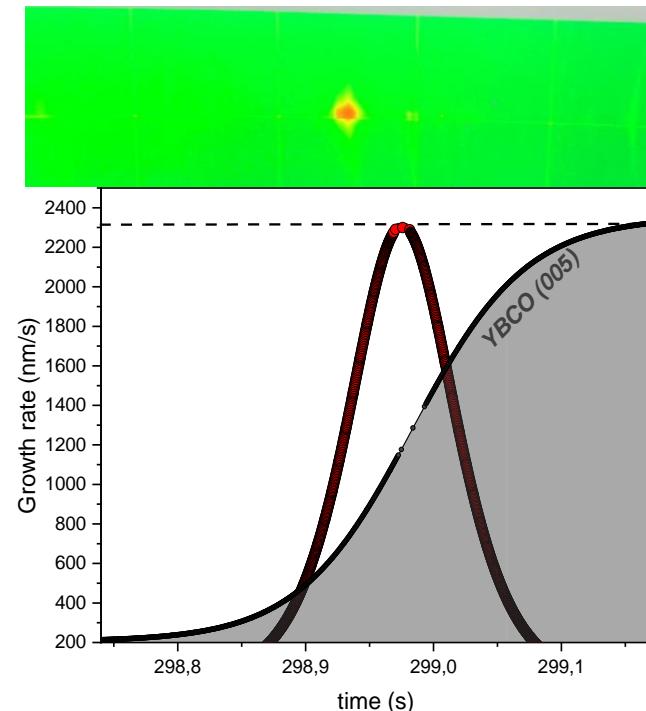
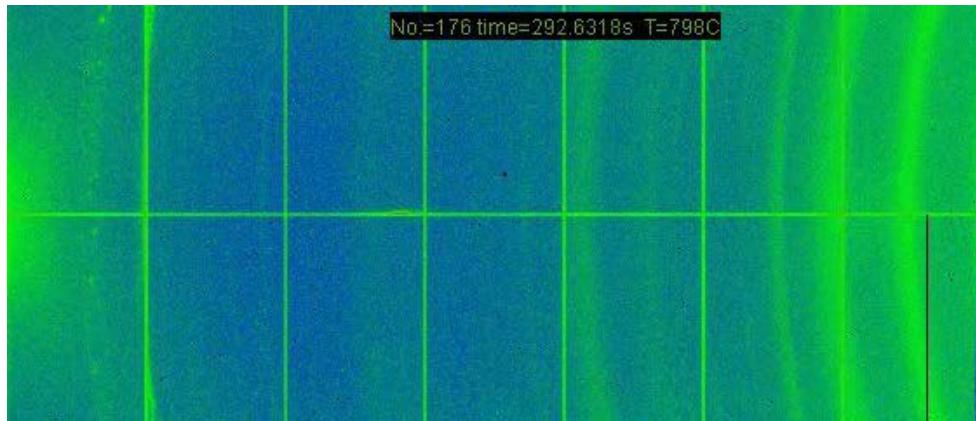
- L. Soler et al., Nat Comm (2020)  
S. Rasi, et al, Advance Science (2022)  
L. Saltarelli et al, ACS Appl. Mat. & Interf. (2022)  
A. Quetalto et al, SUST (2023)

# TLAG in-situ growth evaluation

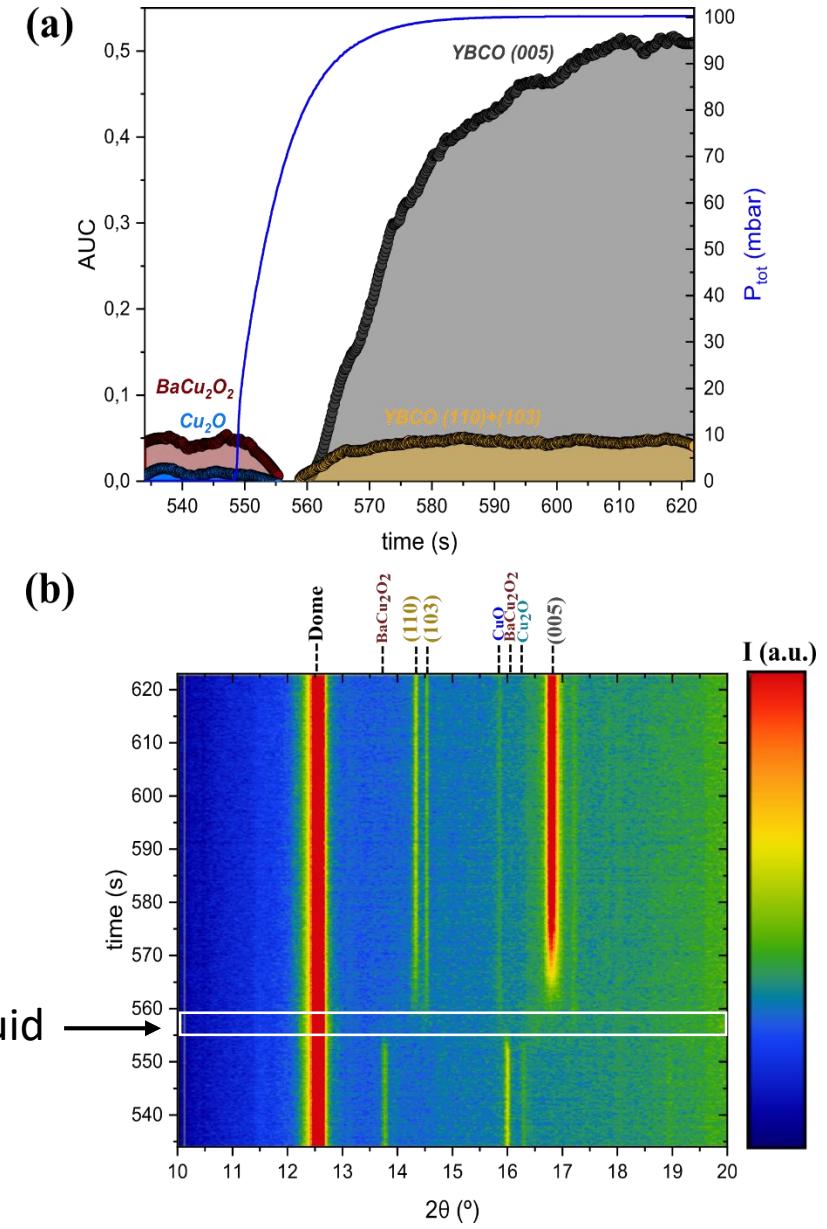


from 100 ms down to 2 ms  
acquisition time

In-situ growth XRD  
synchrotron experiments



Transient liquid →



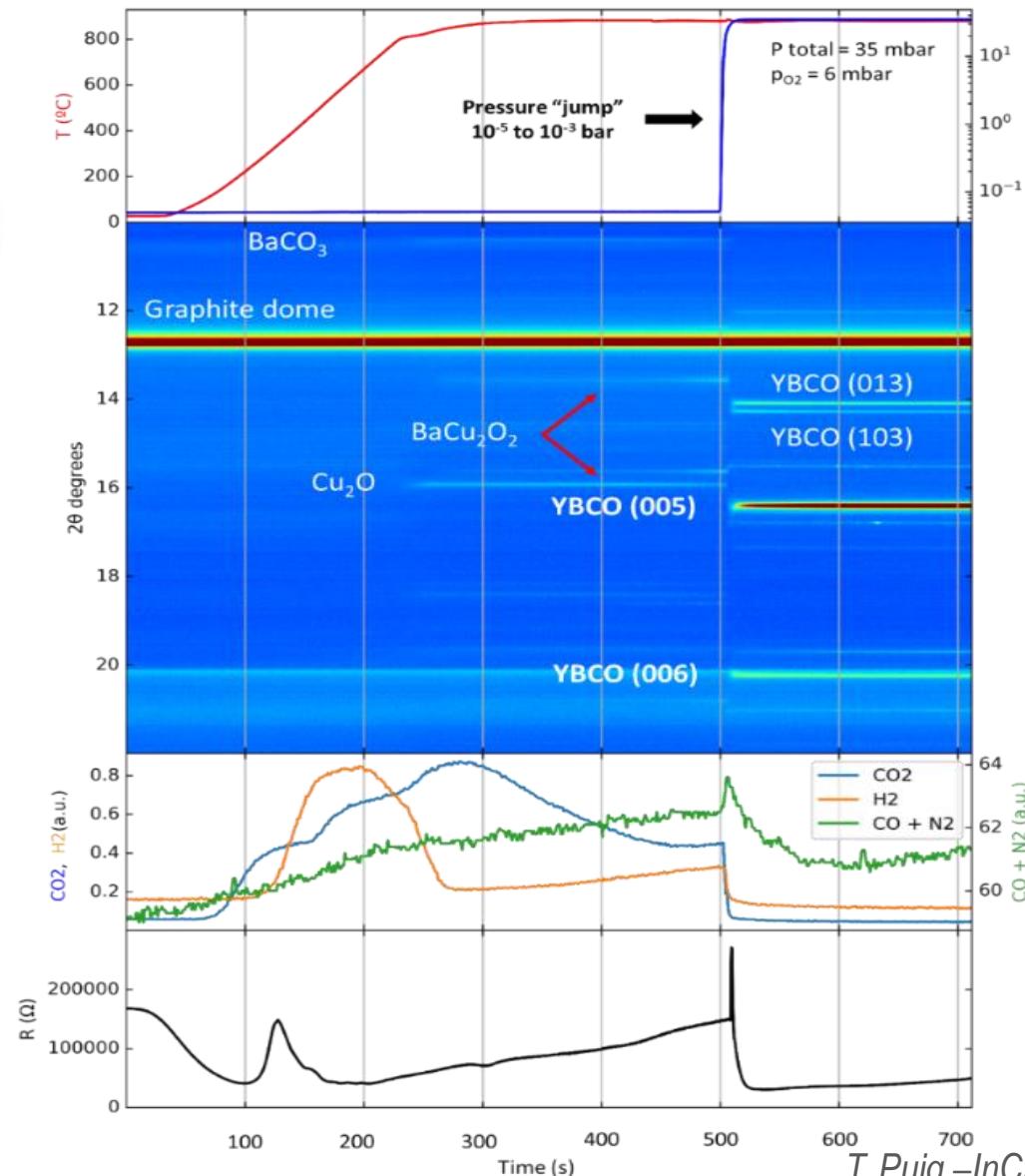
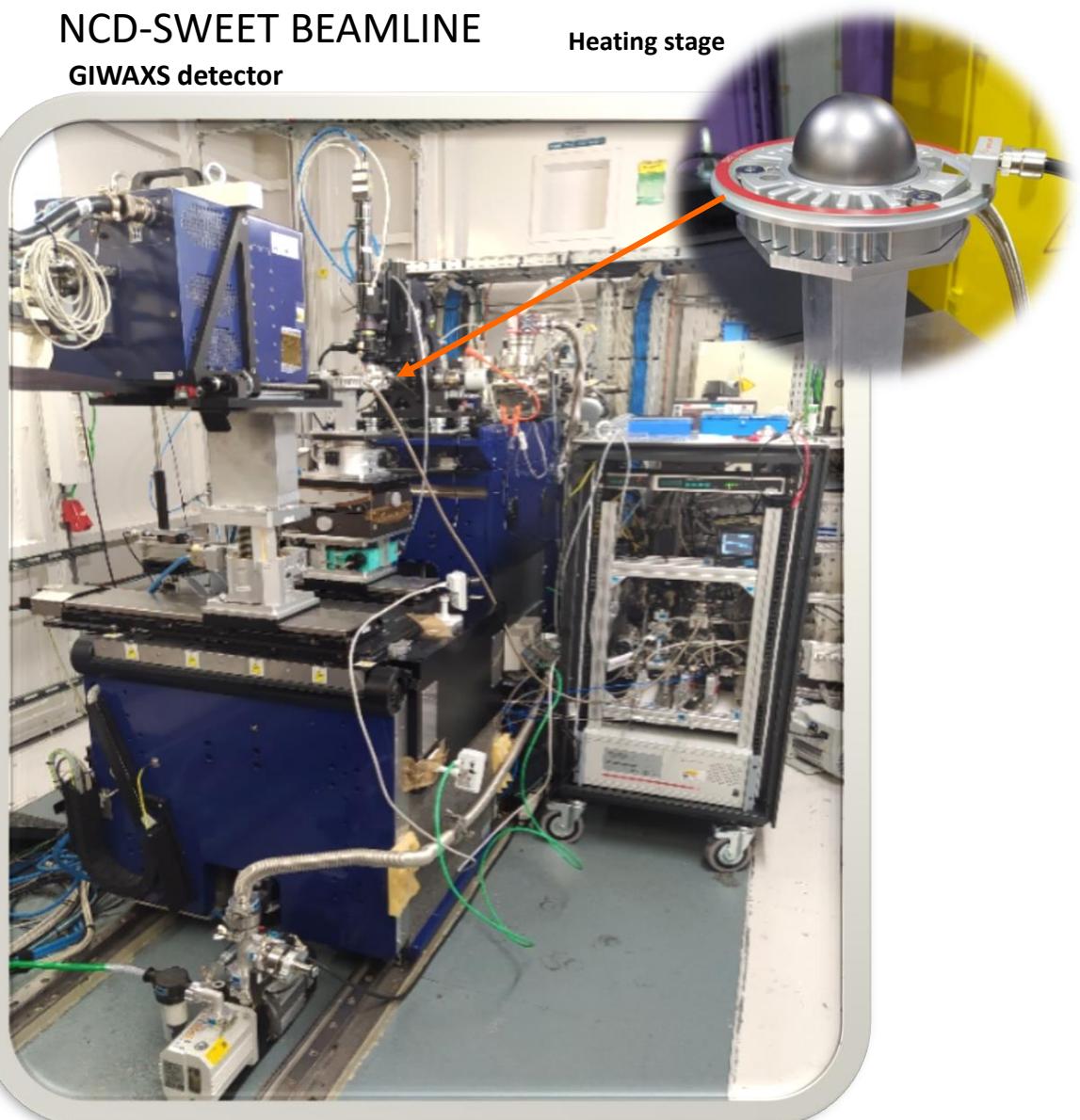
# In-Situ ALBA Synchrotron installation



NCD-SWEET BEAMLINE

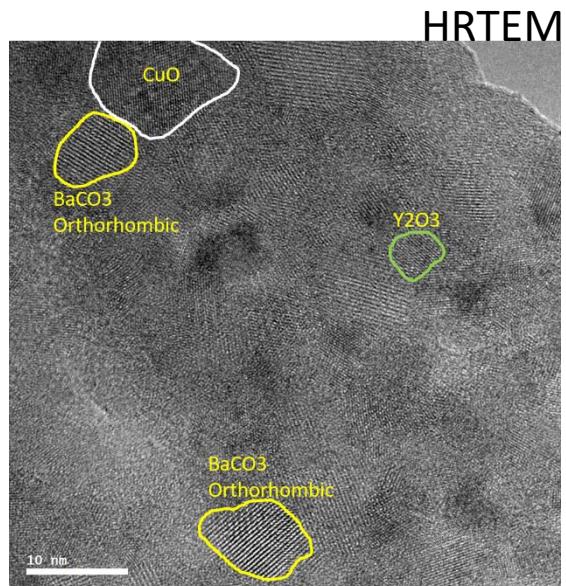
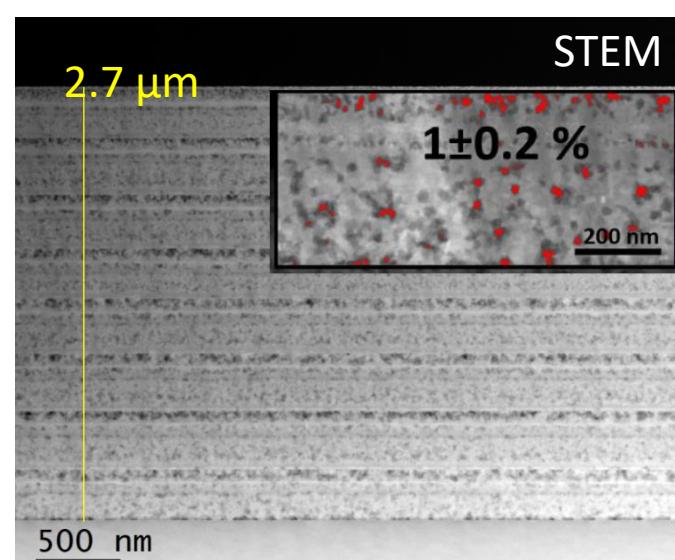
GIWAXS detector

Heating stage



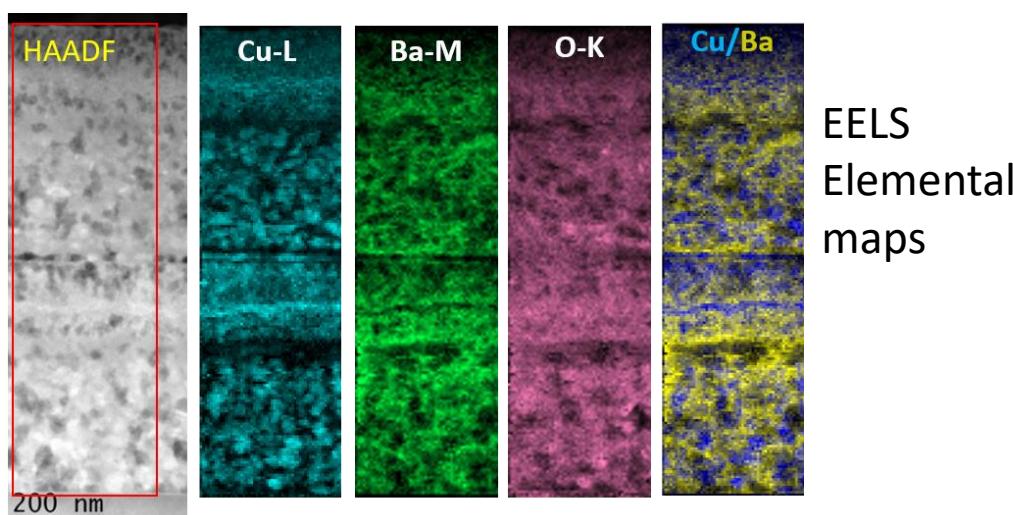
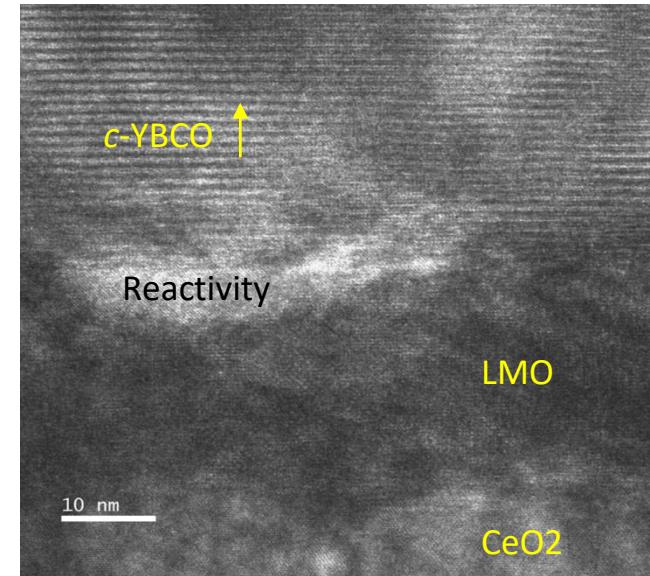
# YBCO TLAG FILMS: Requirements for epitaxial growth

Nanoscale homogeneous and low porosity precursor films

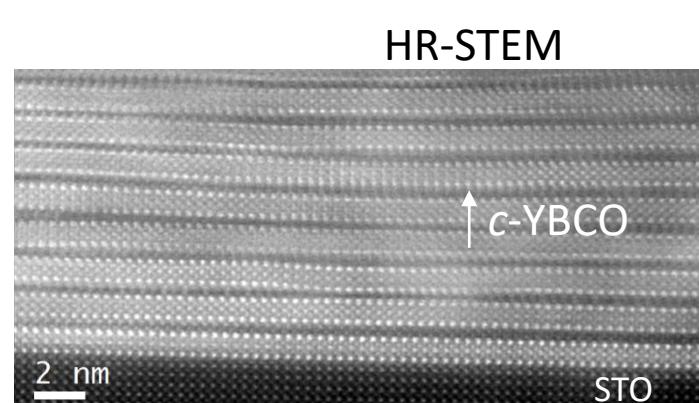


TLAG nucleation  
and growth

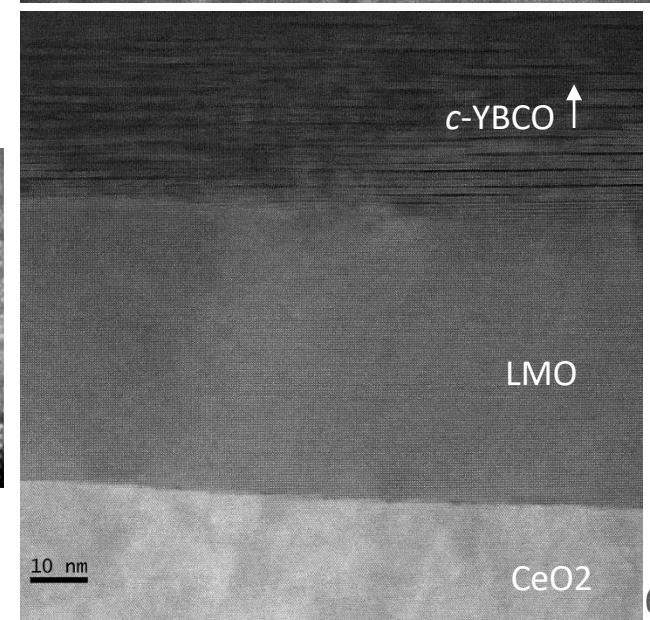
HRTEM



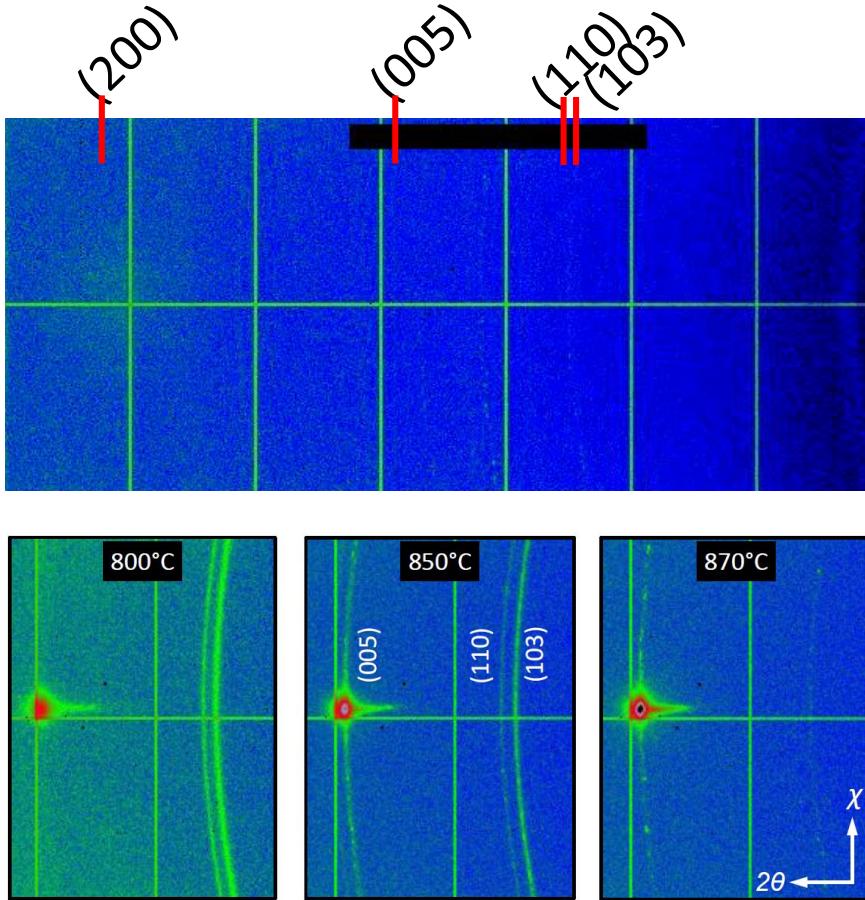
EELS  
Elemental  
maps



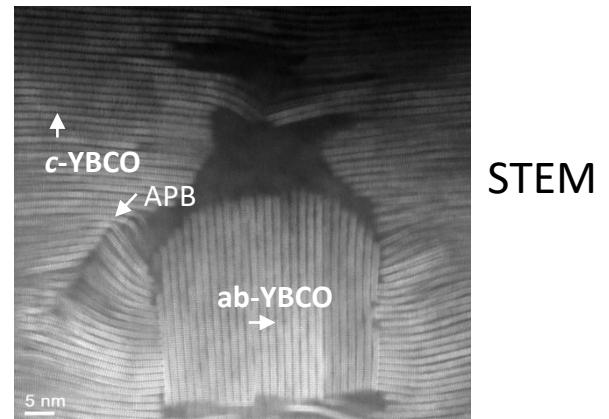
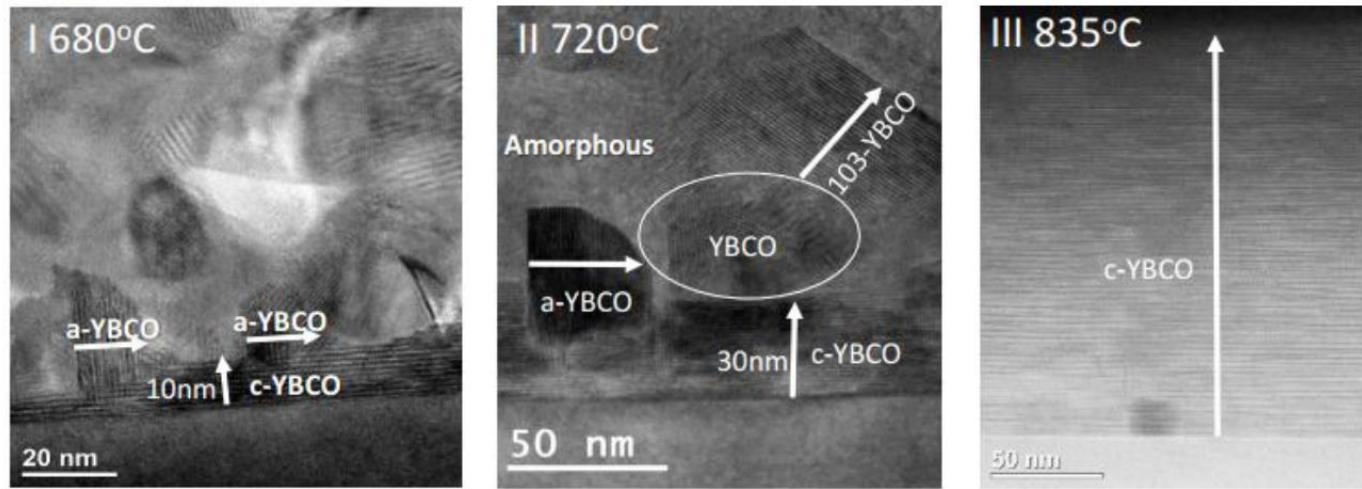
HR-STEM



# Reorientation of small randomly oriented YBCO crystals: correlations between in-situ XRD and TEM



TLAG has the capacity to reorient randomly nucleated YBCO crystals depending on their size and liquid composition

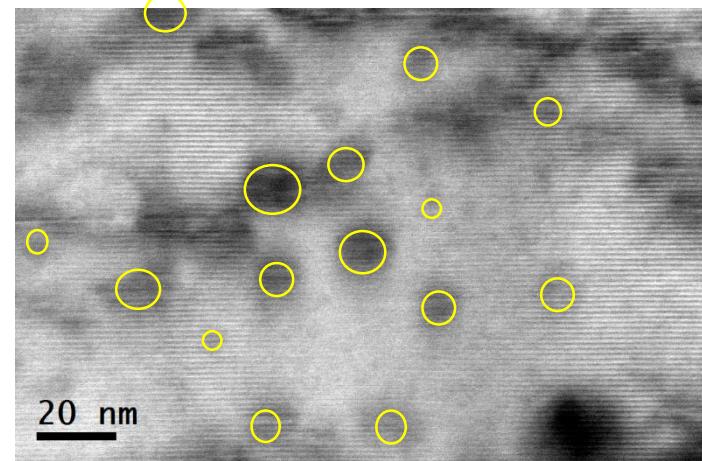


We are able to track the transformation of the random YBCO phase to the epitaxial orientation

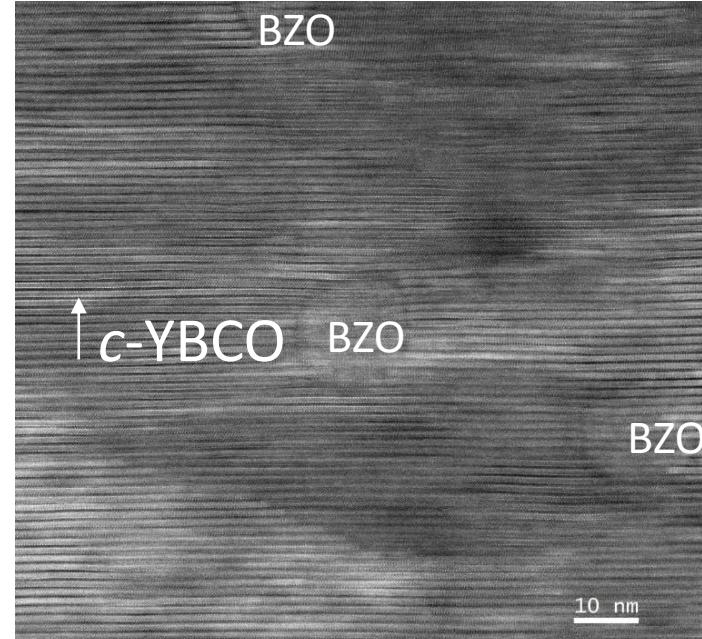
# YBCO TLAG NANOCOMPOSITE FILMS:

## Atomic defects landscape for high field performance

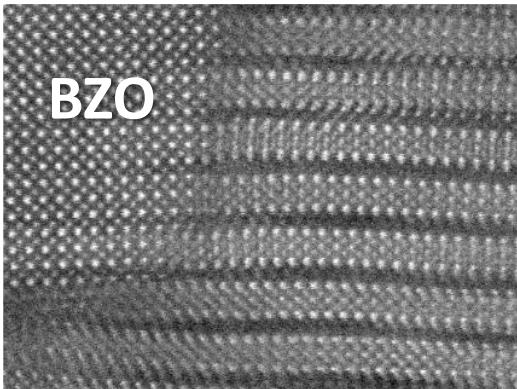
STEM-BF



STEM-ADF

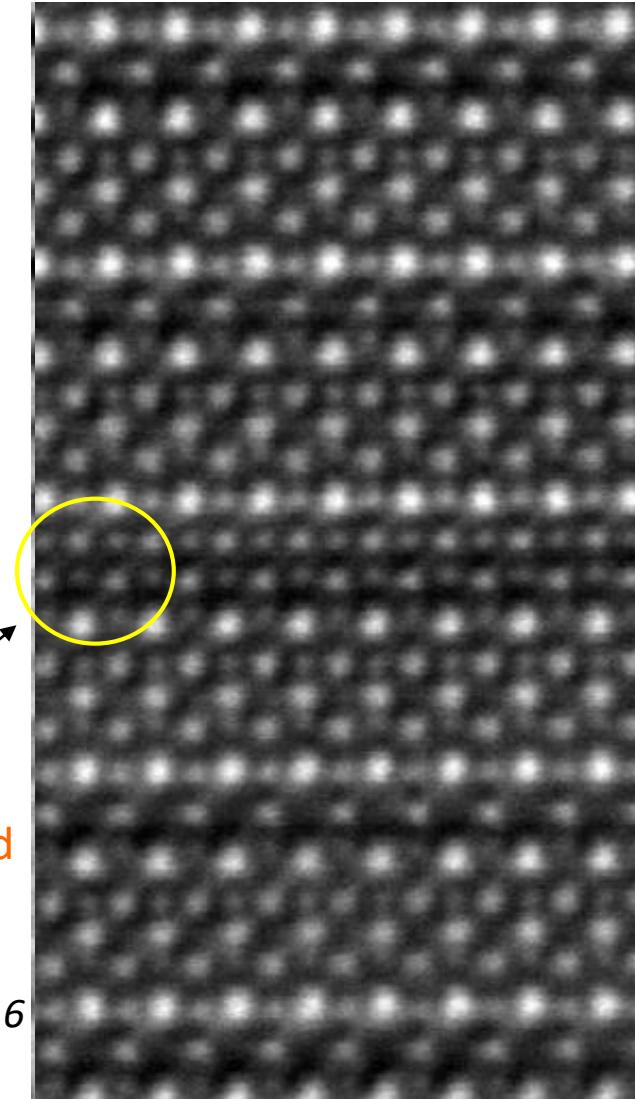


HR-STEM / Annular Dark Field



Intercalation of additional CuO planes

HR-STEM Inverse Annular Bright Field



L.Soler, R. Guzman et al, Nat Comm (2020)

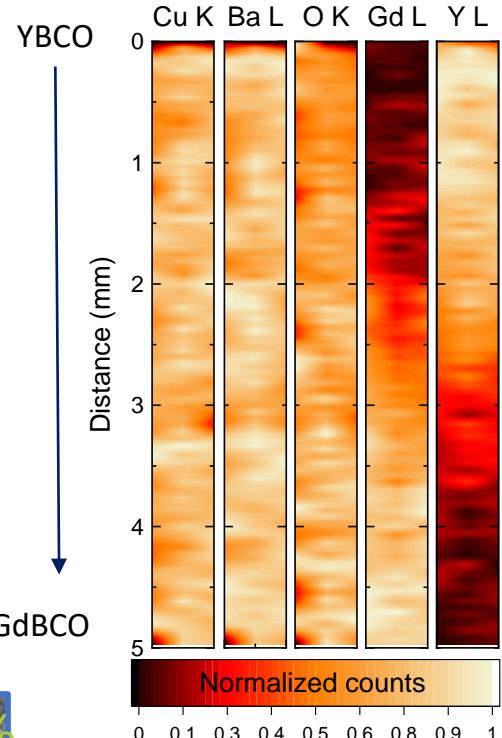
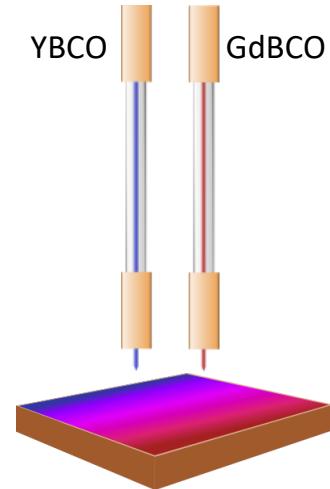
Clusters of  $2V_{Cu} + 3V_{o^-}$  identified  
(supported by EELS)

K. Gupta et al, in preparation

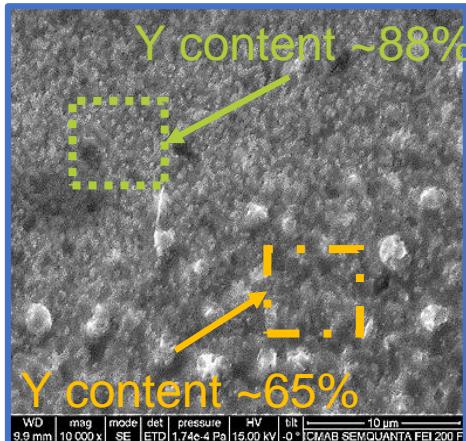
J. Gazquez et al, Adv. Science 2016  
B. Mundet et al, Nanoscale 2020

# High Throughput experimentation: Fast optimization of CC using Compositional Gradients

## Combinatorial DoD Ink Jet Printing



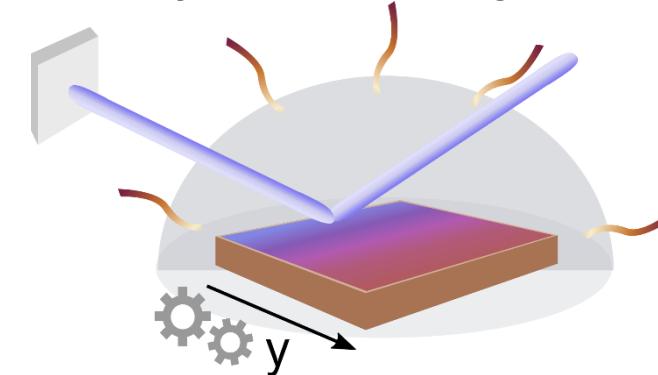
A. Queralto *et al.*, ACS Appl. Mater. Interfaces (2021)



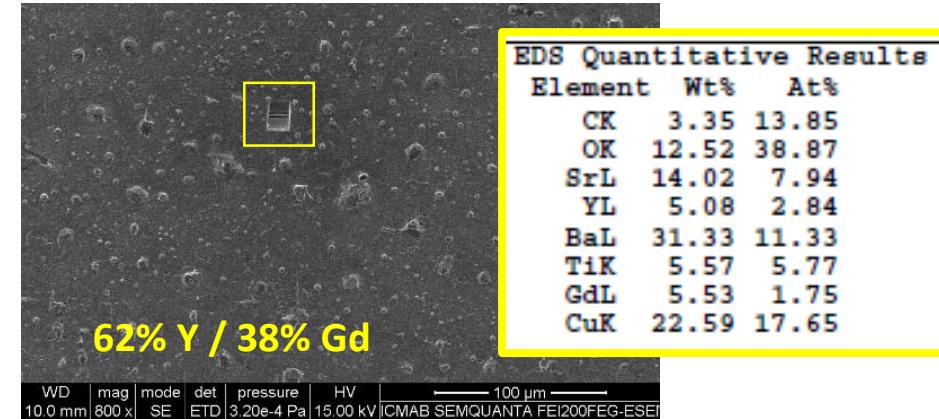
Machine Learning approaches  
initiatives are underway

## Advanced Characterization

### In-situ synchrotron XRD gradients evaluation



### FIB-cut and TEM evaluation in selected places



# Conclusions

- TLAG is a non-equilibrium ultrafast growth process that allows to achieve high performance Coated Conductors at with low cost, high throughput and high scalability
- In-situ Synchrotron XRD experiments are essential to understand the kinetic growth mechanisms and obtain epitaxial layers at ultrafast growth rates
- Probe-corrected Transmission Electron Microscopy and Spectroscopy have proven to be crucial for the identification of the atomic defects that determine superconducting performance
- The combined use of these advanced tools should contribute to the understanding of the TLAG process and its application in industry. We are strongly interested in their use